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Introduction

Graphene Chemiresistors

Results and discussion

Sensing mechanism



- Large surface area
- Chemical stability
- Enormous sensitivity
- Good electrical properties
- Real-time monitoring of the graphene resistance
- Analytes induce an electrical charge transfer into graphene to produce a signal

Can microscopic details of the graphene surface affect the sensing performance of devices?

Polymer Residue



Device fabrication and test setup

Sensor fabrication



Gate voltage measurement indicating the effect that carrier concentration has on graphene's resistance



redistribution between Charge ethanol and graphene responsible for sensing – Theoretical calculation



Graphene surface is coated with PMMA CVD graphene transferred to Si/SiO2 substrates



Details of the sensor design and schematic of experimental setup



- The response to ethanol was evaluated
- High purity nitrogen gas used as a carrier
- Mass flow controllers: to control the concentration of ethanol reaching the sensor







Atomic force microscopy

sensing surface after different baking time at 400 °C.

 \rightarrow less residue with longer baking time

Scanning Tunneling Microscopy and Spectroscopy

STM: After 9 hours, we can image atomically clean surface

STS: The samples are p-doped

Sensing performance after different surface treatments



10h baked

Conclusions and perspectives



Sensors without treatment:

Large variation in response

10h baked best performance:

- Improved sensitivity and reliability
- <u>Further improvement is still needed to</u> <u>narrow the range of the sensor response</u> (device to device variation)

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any gas

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